

## Luminescence Properties of Er implanted n-GaN

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Erbium (Er) -doped semiconductor is a potentially useful material for light-emitting devices in optical communication systems, since the intra-4*f*-shell transitions of Er ions cause sharp and temperature-stable luminescence in various host materials at 1.54  $\mu\text{m}$ , which corresponds to the minimum absorption of silica-based optical fibers. Photoluminescence (PL) from  $\text{Er}^{3+}$  in Er-doped narrow band gap semiconductors (e.g. silicon) is a weak and difficult to observe at room temperature (R.T). Gallium nitride (GaN) is a useful host material because it equips the wide band gap and improves the luminescence properties of the  $\text{Er}^{3+}$  ions. In this work, we implanted Er into undoped epitaxial GaN layer grown on sapphire substrate (GaN:Er) and studied the luminescence properties of  $\text{Er}^{3+}$  ions on annealing temperature, Er dose and temperature dependencies for three kind of atmosphere.

Er implantation energy was performed at 400 keV with a dose range from  $3 \times 10^{13} \text{ cm}^{-2}$  to  $2 \times 10^{15} \text{ cm}^{-2}$  at R.T. Following the ion implantation, these samples were annealed at ranging from 1000 to 1200 for 30 minutes using a rapid thermal annealing.

Fig.1 shows the  $\text{Er}^{3+}$ -related PL spectra of GaN:Er for different Er doses at 15K. Several peaks were observed at around 1.5  $\mu\text{m}$ , and the dominant peak is located at 1537.8nm. The PL intensity of the dominant peak increased with increasing Er dose from  $3 \times 10^{13} \text{ cm}^{-2}$  to  $1 \times 10^{15} \text{ cm}^{-2}$ . In the sample, when Er was implanted into the GaN:Er with a dose of  $1 \times 10^{15} \text{ cm}^{-2}$  the PL intensity of the dominant peak was maximum. Fig.2 shows the  $\text{Er}^{3+}$ -related PL spectra of GaN:Er for different atmosphere. The PL intensity of the dominant peak at 1537.8nm was strongest in atmosphere  $\text{NH}_3:\text{N}_2$  (1:9). Fig.3 shows the temperature dependence of the  $\text{Er}^{3+}$ -related PL intensity. It is clear that there are some thermal quenching processes on these grounds, we conclude that  $\text{Er}^{3+}$  forms some complex centers with N in GaN:Er and that at least two complex centers contribute to the luminescence of GaN:Er.

By investigating the temperature dependence of the  $\text{Er}^{3+}$ -related PL intensity, we found that thermal quenching of the luminescence of  $\text{Er}^{3+}$  was suppressed by using GaN as a host material instead of Si, and that  $\text{Er}^{3+}$  forms at least two Er-N complex centers with N which contribute to the luminescence of  $\text{Er}^{3+}$  in GaN:Er.

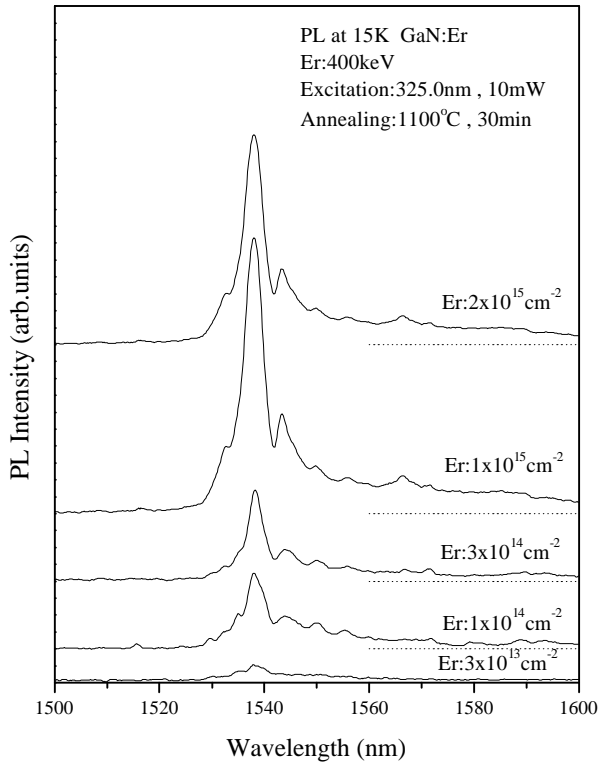


Fig.1. The  $\text{Er}^{3+}$ -related PL spectra of GaN:Er for different erbium dose.

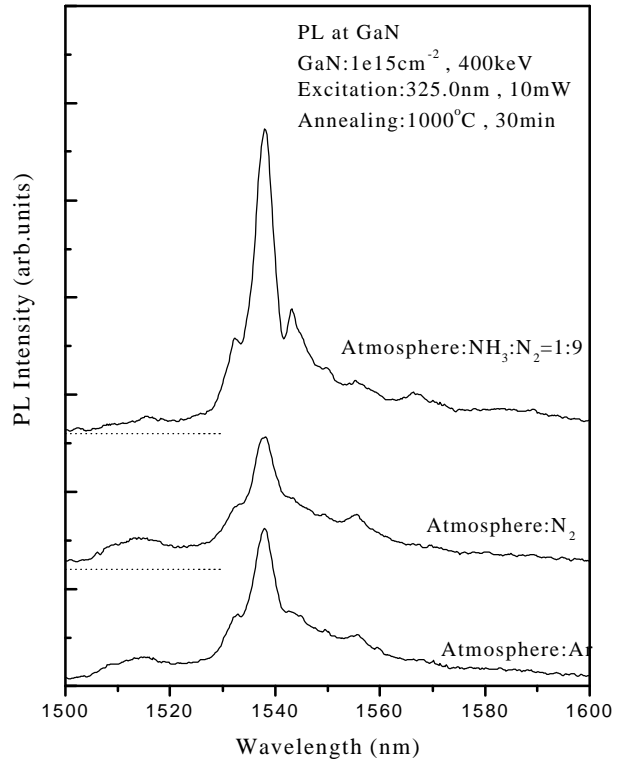


Fig.2. The  $\text{Er}^{3+}$ -related PL spectra of GaN:Er ( $\text{Er}:1 \times 10^{15} \text{ cm}^{-2}$ ) for different atmosphere.

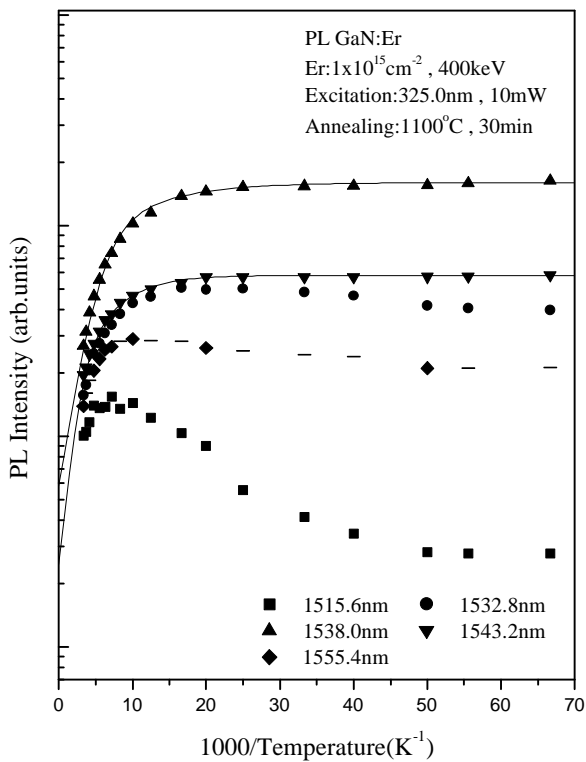


Fig.3. Temperature dependence of PL intensity in GaN:Er annealing at 1100

#### Reference

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